



SEMICONDUCTOR



PHOTOVOLTAIC



LED



CHEMICAL
INDUSTRY



LA+

COMBUSTION EXHAUST GAS ABATEMENT



The semiconductor manufacturing industry increasingly employs a variety of specialized gases, making it essential not only to abate them safely but also to minimize reactive byproducts that can hinder continuous operation. By addressing these needs, EBARA has developed the new Model LA+, which enhances processing and durability performance over its predecessor, Model TND.

BENEFITS

- Reduction of byproduct adhesion and NOx/COx emissions
- Compact design for space efficiency
- Hydrogen fuel option
- Maximum airflow capacity of 600L/min



Technical Data

Size (WxDxH) in mm 1200 x 700 x 990

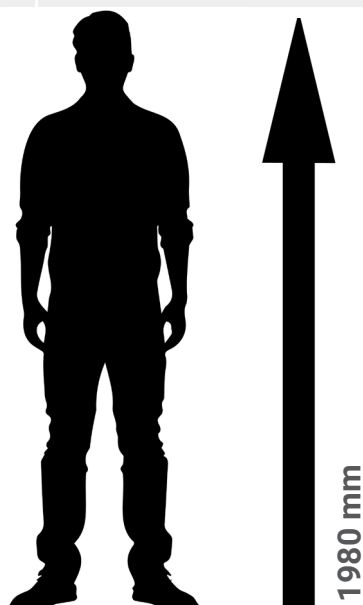
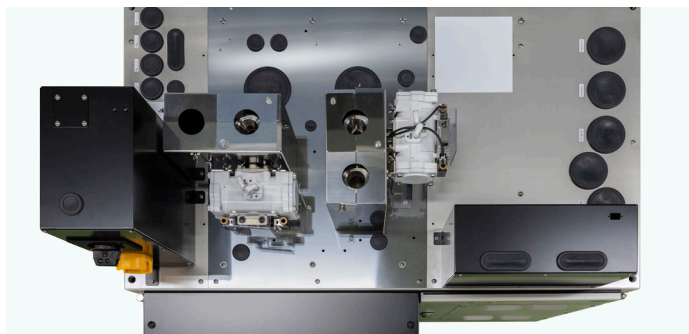
Weight in kg 380

Maximum Inlet Connections 4 or 6-inlet model

Maximum Gas Inflow 600L/min (future high-capacity versions)

Fuel Options Hydrogen, city gas, propane

Compatible Processes ALD, PE-CVD, LP-CVD, Etching



FREE SPACE
to put another
device



All data without guarantee.

APPLICATIONS FOR LA+

ALD

PE-CVD

LP-CVD

Etching

For further information, technical data or drawings please contact  marketing@ebar-pm.eu

EBARA is a worldwide leading global manufacturer of vacuum and semiconductor systems used in the production of wafers, liquid crystals, solar cells and other products requiring advanced technology.

EBARA supports



EBARA Precision Machinery Europe (EPME) is part of the Japanese EBARA Group and employs approximately 230 people in Europe. The portfolio includes dry and turbo molecular vacuum pumps as well as gas abatement systems. In addition, EPME sells state-of-the-art CMP tools, wafer bevel polishing and substrate coating systems. In Europe, EPME has a central warehouse and two overhaul centres for vacuum pumps.

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